| Ref # | Hits | Search Query | DBs | Default Operator | Plurals | Time Stamp |
|----------|--------|---|---|---------------------|---------|------------------|
| L2 | 254984 | (remov\$3 or stripp\$3 or etch\$3) same oxide | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | OFF | 2004/11/21 08:31 |
| L3 | 320 | 2 same ((transfer\$3 or load adj lock) near chamber) | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | OFF | 2004/11/21 08:33 |
| L4 | 219 | 3 same (wafer or semiconductor) | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | OFF | 2004/11/21 08:33 |
| L5 | 101 | 4 and @pd<"20010111" | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | OFF | 2004/11/21 08:50 |
| L6 | 32 | 4 same ((vapor\$3 near solution) or (hydrofluoric or "HF")) | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | OFF | 2004/11/21 09:17 |
| L7 | 3 | pas-sylvia-h.in. | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | OFF | 2004/11/21 09:17 |